

REMARKS

Entry of the above amendment and reconsideration of the above-referenced application in view of the above amendment, and of the following remarks, is respectfully requested.

Claims 28-33 are pending in this application. Claims 28-33 are added herein.

The Examiner rejected claims 1-3, 5, 6, 9-13, 15 and 16 under 35 U.S.C. § 102(e) as being anticipated by Dabbaugh et al. (U.S. Patent No. 6,362,094 B1). These claims have been cancelled.

The Examiner rejected claims 4 and 14 under 35 U.S.C. § 103(a) as being unpatentable over Hasegawa as applied to claim 1, and further in view of Schrantz et al. (U.S. Patent No. 5,650,639). These claims have been cancelled.

The Examiner rejected claims 7 and 17 under 35 U.S.C. § 103(a) as being unpatentable over Dabbaugh et al. as applied to claims 1 and 11 above, and further in view of Hasegawa (U.S. Patent No. 5,646,440). These claims have been cancelled.

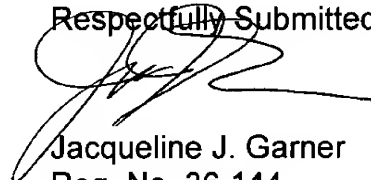
The Examiner rejected claim 8 under 35 U.S.C. § 103(a) as being unpatentable over Dabbaugh et al. in view of Hasegawa and further in view of Chooi et al. (U.S. Patent No. 6,465,888 B2). This claim has been cancelled.

Applicant respectfully submits that newly added claims 28 is patentable over the references of record as there is no disclosure or suggestion in the references of a liner comprising silicon and carbon located on and between metal interconnect lines and a dielectric layer positioned between the metal interconnect lines, wherein the liner is positioned between at least a portion of the dielectric layer and the metal interconnect lines. Dabbaugh teaches a silicon carbide liner over a gate electrode. Conductive elements 140 in Dabbaugh are gate electrodes and not metal interconnect lines as required by the claim. Furthermore, the liner 210 is not located "on" the gate electrodes 140, much less "on" metal interconnect lines as claimed. The references as combined fail to teach this limitation. Accordingly, Applicant respectfully submits that claim 28 and the claims dependent thereon are patentable over the references of record.

In light of the above, Applicant respectfully requests withdrawal of the Examiner's rejections and allowance of claims 28-33. If the Examiner has any questions or other correspondence regarding this application, Applicant requests that the Examiner contact Applicant's attorney at the below listed telephone number and address.

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Respectfully Submitted,



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